



BASIC ENERGY SCIENCES – Serving the Present, Shaping the Future http://www.science.doe.gov/bes

# **Basic Energy Sciences**

#### Beta Test of Alternative Metrics for Assessing the BES Light Sources

Patricia M. Dehmer Director, Basic Energy Sciences October 2005

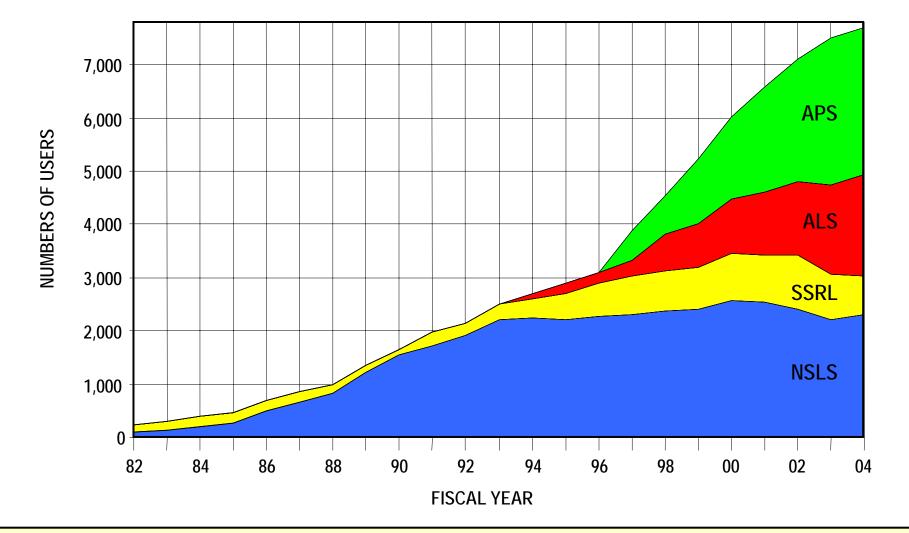


# **BES Facilities for X-ray Scattering**



Stanford Synchrotron Radiation Laboratory

#### A New Methodology for Assessing Utilization of the Synchrotron Radiation Light Sources (and, by extension, the other BES user facilities, too)



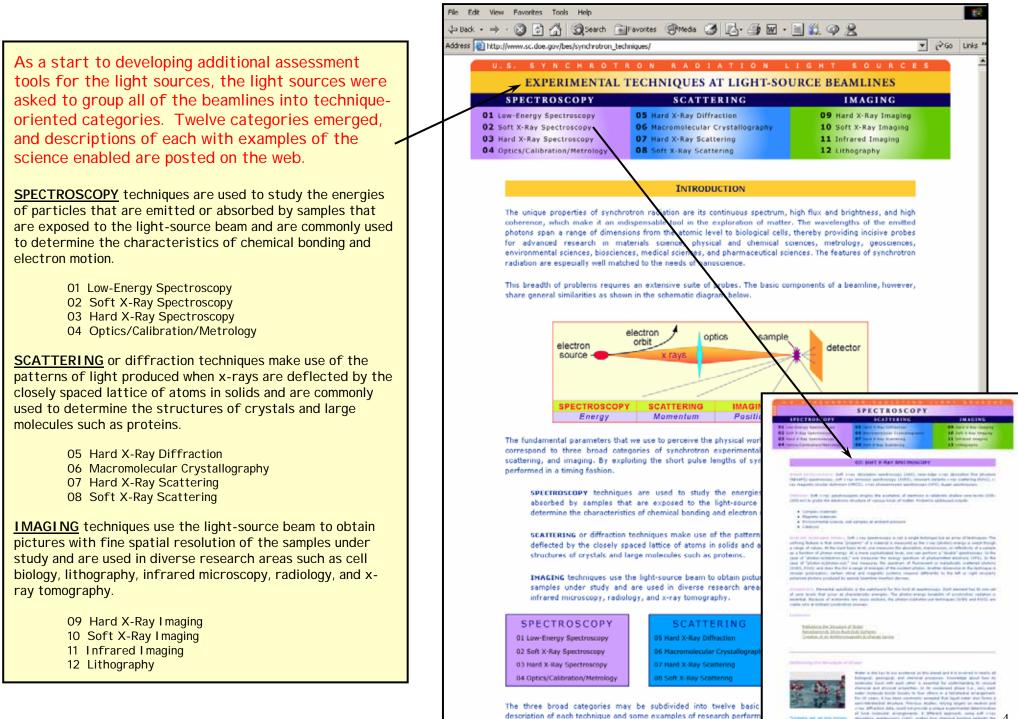
In FY 2006, the four BES light sources accounted for 44% of the BES facilities budget and 21% of the total BES budget excluding construction. They are visited by nearly 8,000 users per year.

Synchrotron radiation light sources command national-level attention, because they enable scientific investigations in areas closely aligned with national priorities including nanotechnology, energy security, defense technologies, and biomedical research. The scientific progress and hence the relative international competitive position of U.S. research efforts depend to an extent upon the overall capability and efficient utilization of U.S. synchrotron radiation light source facilities.

Effective utilization means maximizing science output. In turn, this means that we must measure more than the operation of the accelerator complex. We also must look to the "user experience" to determine the overall effectiveness of the facility.

#### Assessments of the BES Light Sources

http://www.sc.doe.gov/bes/synchrotron\_techniques/



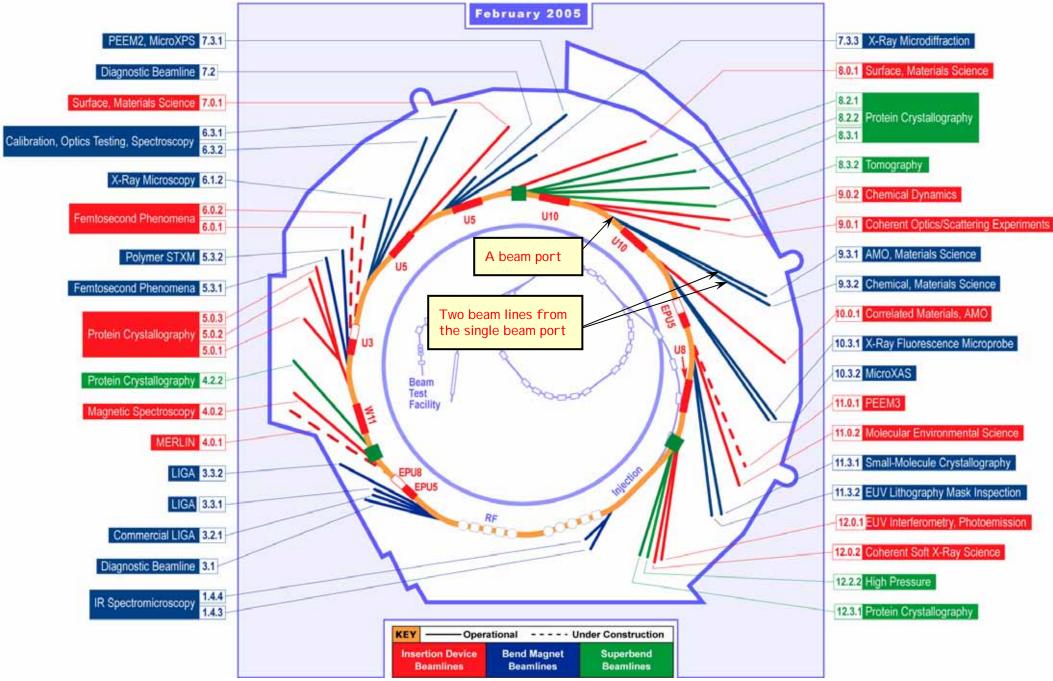
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### Beamline Matrix – Advanced Photon Source (44)

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		DESCRIPTIONS of 12 TECHNIQUES:		Perc	entage				hat is a					The su	im of					
				_		pe	ercenta	ges eq	uals 10	0% for	each b	beamlir	ne.				F	Y 2004	4	
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Then each light so		pe.gov/bes/synchrotron_techniques/index.htm																		
mapped every one	ofits			s	pectr	oscop	зу		Scatt	ering			Imag	ging						
operating beamline	es onto a				do:			<u>د</u>		6	_								Obach (M) margin	
matrix of the 12 to					So			ctio		erin	ung	<u>p</u>	ē					c	Check (X) mear that the beamlin	
	coninques.				Soft x-ray spectroscop)	<u> </u>	Optics; calibration; metrology	Hard x-ray diffraction	Macromolecular crystallography	scattering	Soft x-ray scattering	Hard x-ray imaging	Soft x-ray imaging				iť	Designation	is "Best in Class	s"
<b>T</b> erestlese there ar	170			Low energy spectros copy	ds /	Hard x-ray spectroscopy	ibrat	ýd	grap	iy si	/ sc	ay in	, m	g	ç	#	Facility	sign	as bench-marke against similar	ed
Together, there ar				lene	(-ra)	X-re ros	; cal	a-x	ollog	Hard x-ray	(-ra)	X-18	(-ra)	IR imaging	Lithography		<sup>u</sup>	Det	capabilities	
operating beamline		Beamline Type	Count	owe	f	ard	etrol	ard	ysta	ard	off	ard	off	Ē	tho				worldwide	
four BES light sou	rces. There	Beamine Type	0													0		1.0	1.	<b>_</b>
are another ~100 k	beamlines			01	02	03	04	05	06	07	08	09	10	11	12	0		onal Bea	amlines	
that have never be		raction, and imaging	1					30		40		30				1		01-BM		
instrumented or th		raction, and imaging	2					35		35		30				1		01-ID		
		ffraction	3					30				70				1		02-BM	Х	
obsolete instrumer	intation.	attering	4								30		70			1		02-ID-B	Х	Z
			5		L			10				90				1		02-ID-D	Х	
Note, though, that	t not all 100		6	L								100				1		02-ID-E		$-1$ $\setminus$
of these "open" spa	aces for		7				20			80						1		03-ID	X	$ \rightarrow $
beamlines could be		cattering, and imaging	8		40	2.2					30		30			1		04-ID-C	<u> </u>	
into "best-in-class"			9			20		60				20				1		04-ID-D	Х	Note: The che
		nd diffraction	10	<u> </u>		50		50		F.0						1	-	05-BM-C		marks indicate
This is due primari		scattering	11					50	EO	50						1		05-BM-D		beamlines that
limitations on the l		graphy and hard x-ray diffraction and scattering	12					25 50	50	25 50						1		05-ID 06-ID		are "best in
experimental floor		scattering	13					50		50						1		06-ID 06-ID-D		
ultimate brightnes	ss of the	scattering	14	-				100		50						1		06-ID-D 07-ID	+	class."
beam from the bea		graphy	15					100	100							1		07-1D 08-BM	╡	
example, at the AP		scattering	10					50	100	50						1		08-ID		-
		Source mg	17					5		95		<u> </u>				1		09-ID		-
of the uncommitte			18			70		30		,,		<b>⊢</b> -ſ						10-ID		-
high brightness ins	sertion		20					100					Note					11-ID-B		-
device lines.			20					100					ports	" – w	nich a	are	AP	11-ID-C		-
		nd diffraction	22			50		50					, the p					11-ID-D		-
Ha	rd x-ray spectroscopy a		23			50		50					openi			rav		12-BM		
	rd x-ray diffraction and		24			-		50		50								12-ID	Х	
		ectroscopy, and imaging	25			25		50				25	radia					13-BM	Х	7
		ectroscopy, scattering, and imaging	26			35		35		15		15	elect				APS	13-ID	Х	
	acromolecular crystallo		27						100				ring -	- can	suppo	ort		14-BM-C		
	acromolecular crystallog		28						100				more	than	one		APS	14-BM-D		
Ma	acromolecular crystallog	graphy	29						100				"bean	nline	" See	e		14-ID		
Ha	rd x-ray diffraction		30					100					exam					15-ID	Х	
	ard x-ray diffraction and		31					50		50				•				16-ID-B	Х	
	acromolecular crystallog		32						100				Adva					17-BM		_
	acromolecular crystallog	graphy	33						100				Sourc		tne r	iext		17-ID		_
	rd x-ray scattering		34			20				80			chart					18-ID		_
	Macromolecular crystallography Macromolecular crystallography		35	<u> </u>					100			_ ∟		1				19-BM	X	_
			36			100			100							1		19-ID	Х	
	Hard x-ray spectroscopy Hard x-ray spectroscopy and diffraction Macromolecular crystallography Macromolecular crystallography	1.1100 - 41	37			100		F.0								1		20-BM		_
			38			50		50	100							1		20-ID	Х	
			39						100							1		22-BM	V	-
		• • •	40	-					100							1		22-ID	X	-
	acromolecular crystallo	grapny	41			100			100							1		31-ID		-
	rd x-ray spectroscopy	- the second second in the second secon	42			100		40		20		20				1	_	33-BM 33-ID	V	
	rd x-ray diffraction, spe rd x-ray imaging	ectroscopy, scattering, and imaging	43					40 20		30		30 80				1		33-ID 34-ID	Х	
Ha	uu x-ray maging		44					20				30				1	ni S	J4-1D		

#### The Difference Between Beam Ports and Beam Lines

Example from the Advanced Light Source



## Beamline Matrix – Advanced Light Source (35)

					l	Jtiliza	tion N	/latrix	for th	ne Fou	r DOE	E/BE	3 Light	Sour	ces		
					B	EAML	INE T	ECH	NIQUI	ES							
DESCRIPTIONS of 12 TECHNIQUES:		Perc	entade	e for ea	ch tech	niaue t	hat is a	vailabl	e on ea	ach bea	mline.	The s	sum of				
										beamlin					-	v	
										1					-	Y 2004	•
http://www.sc.doe.gov/bes/synchrotron_techniques/index.htm																	
		s	nectr	osco	v		Scatt	ering	1		Imag	aina					
		Ŭ	<u> </u>		- <b>-</b>		ooutt	loning	,		inna	99					
Beamline Type	Count	Low energy spectros copy	Soft x-ray spectroscop	Hard x-ray spectroscopy	Optics; calibration; metrology	Hard x-ray diffraction	Macromolecular crystallography	Hard x-ray scattering	Soft x-ray scattering	Hard x-ray imaging	Soft x-ray imaging	IR imaging	Lithography	#	Facility	Designation	Check (X) means that the beamline is "Best in Class" as bench-marked against similar capabilities worldwide
Low energy spectroscopy and IR Imaging	45	50			02	-	~ 0	-	~~~	-		50		1	ALS	1.4.3	
IR imaging	46	25										75		1		1.4.4	
Lithography	47												100	1		3.2.1	Х
Lithography	48												100	1	ALS	3.3.1	X
Lithography	49												100	1	ALS	3.3.2	X
Soft x-ray spectroscopy	50		95								5		100	1		4.0.2	X
Macromolecular crystallography	51						100							1		4.2.2	X
Macromolecular crystallography	52						100							1		5.0.1	
Macromolecular crystallography	53						100							1		5.0.2	1 X
Macromolecular crystallography	54						100							1		5.0.3	7
Hard x-ray diffraction	55					100								1		5.3.1	
Soft x-ray spectroscopy and soft x-ray imaging	56		50								50			1	ALS	5.3.2	
Soft x-ray imaging	57										100			1	ALS	8.1.2	Х
Soft x-ray spectroscopy	58		100											1	ALS	6.3.1	
Optics; calibration; metrology	59		20		80									1	ALS	6.3.2	Х
Low energy spectroscopy	60	50	25						25							0.1	Х
Soft x-ray imaging	61										100		A larg	e num	ber	3.1.1/2	Х
Hard x-ray imaging	62									100			of bea	mline	s at	3.3	
Soft x-ray scattering and spectroscopy	63		50						50				the Al	LS are	ż	0.1	
Macromolecular crystallography	64						100						rated			2.1	Х
Macromolecular crystallography	65						100						class."			2.2	Х
Macromolecular crystallography	66						100						01035.			3.1	Х
Hard x-ray imaging	67									100				1	ALS	8.3.2	
Low energy spectroscopy	68	80									20			1	ALS	9.0.1/2	Х
Soft x-ray spectroscopy	69		100											1		9.3.1	
Soft x-ray spectroscopy	70	20	80											1	ALS	9.3.2	
Low energy spectroscopy	71	100												1		10.0.1.1/2	Х
Hard x-ray imaging	72									100				1	ALS	10.3.1	
Hard x-ray imaging, diffraction, and spectroscopy	73			25		25				50				1	ALS	10.3.2	Х
Soft x-ray spectroscopy	74		50						20		30			1	ALS	11.0.2	Х
Hard x-ray diffraction	75					100								1		11.3.1	
Optics; calibration; metrology	76				100									1		11.3.2	Х
Lithography, low energy spectroscopy, and soft x-ray imaging	77	30									20		50	1		12.0.1.1/2	Х
Hard x-ray diffraction	78					100								1		12.2.2	
Macromolecular crystallography	79						70	30						1	ALS	12.3.1	Х

## Beamline Matrix – National Synchrotron Light Source (77)

					ι	Jtiliza	tion N	/latrix	for th	ne Fou	ır DOE	E/BES	Light	t Sour	ces		
					B	EAML	INE T	ECH	NIQU	ES							
DESCRIPTIONS of 12 TECHNIQUES:		Perc	entade	for ear						ach bea	mline	The si	im of				
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				P1	oonta	900 04		0 /0 101	Cuon	Joanni	10.				- F	Y 200	4
http://www.co.doo.gov/boo/ovpohratrop_toohniguoo/indox.htm																	
http://www.sc.doe.gov/bes/synchrotron_techniques/index.htm		6	nootr				Scatt	oring			Ima	aina					
		3	· · ·	oscop	у		Scall	enng	9		Ima	ging					
Beamline Type	Count	Low energy spectroscopy	Soft x-ray spectroscop)	Hard x-ray spectroscopy	Optics; calibration; metrology	Hard x-ray diffraction	Macromolecular crystallogra phy	Hard x-ray scattering	Soft x-ray scattering	Hard x-ray imaging	Soft x-ray imaging	IR imaging	Lithography	#	Facility	Designation	Check (X) means that the beamline is "Best in Class" as bench-marked against similar capabilities worldwide
Soft x-ray spectroscopy	80	~ ~	100	тs	0 5		20	-		<u> </u>	- "			1	NSLS	1114	
Low energy spectroscopy	81	100	100											1	NSLS		
	82	30										70		1	NSLS		
IR imaging Optics; calibration; metrology	82	50			100							70		1	NSLS		
	83	50			100							50		1	NSLS		
Low energy spectroscopy and IR Imaging	85	100							+			50			NSLS		
Low energy spectroscopy	85	100	80						20					1	NSLS		
Soft x-ray spectroscopy	86	100	80						20					-	NSLS		
Low energy spectroscopy	_	100	100											1			
Soft x-ray spectroscopy	88	100	100											1	NSLS		
Low energy spectroscopy	89	100												1	NSLS		
Soft x-ray spectroscopy	90		100											1	NSLS		
Optics; calibration; metrology	91				100				-					1	NSLS		
Low energy spectroscopy	92	100												1	NSLS		
Low energy spectroscopy	93	100												1	NSLS		
IR imaging	94											100		1	NSLS		
Low energy spectroscopy	95	100												1	NSLS		
Low energy spectroscopy	96	100												1		U12IR	X
Soft x-ray spectroscopy	97		100											1	NSLS		/
Low energy spectroscopy	98	100												1	NSLS		X
Optics; calibration; metrology	99				100									1	NSLS		
Soft x-ray spectroscopy	100		100											1	NSLS		
Soft x-ray imaging	101										100			1	NSES	X1A1	
Soft x-ray imaging	102										100			1	NSLS		
Soft x-ray scattering and spectroscopy	103		30						70							1B	Х
Hard x-ray imaging	104									100				vely f		2B	
Hard x-ray diffraction	105					100							beaml	ines a	t the	3B1	
Macromolecular crystallography	106						100						NSLS	are r	ated	4A	
Macromolecular crystallography	107						100							in clas		4C	
Hard x-ray diffraction	108					100							2001	orac		5A	
Macromolecular crystallography	109						100							1	NSLS	X6A	
Hard x-ray diffraction	110					100								1	NSLS		
Hard x-ray diffraction	111					100								1	NSLS		
Hard x-ray diffraction	112					100								1	NSLS		
Optics; calibration; metrology	113				100									1	NSLS	X8A	
Macromolecular crystallography	114						100							1	NSLS		
Macromolecular crystallography	115						100							1	NSLS		
Hard x-ray spectroscopy	116			100										1	NSLS		
Hard x-ray scattering	117					30		70						1	NSLS		

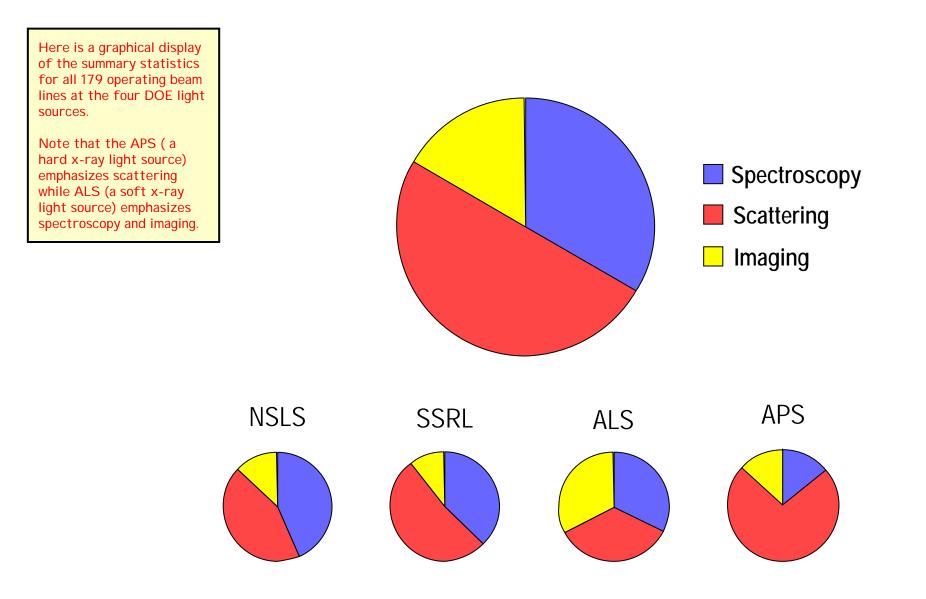
### Beamline Matrix – National Synchrotron Light Source (77)

				cont	inuec	<b>/</b>											
					ι	Jtiliza	tion N	Aatrix	for th	e Fou	ir DOE	BES	Light	Sour	ces		
									NIQU								
DESCRIPTIONS of 12 TECHNIQUES:		Perc	ontorio	for ear					le on ea		mline	The er	mof				
DEGCKIT HONG OF 12 FEGHINIQUED.		Feic	entage						r each b			TH <del>e</del> st	in or		_		
				P	sicenta	963 64	uais it	/0 /0 101	Gacin	Jeannin	10.				F	Y 200	4
http://www.sc.doe.gov/bes/synchrotron_techniques/index.htm																	
http://www.sc.doe.gov/bes/synchronon-techniques/index.ntm		s	pectr	oscop	οv		Scatt	tering	1		Ima	qinq					
			· · ·	Г <sup>с</sup>	ĺ	-			Í								
			Soft x-ray spectroscop)			Hard x-ray diffraction		Hard x-ray scattering	ing	g	p					_	Check (X) means that the beamline
			ectr		iii	ffrac	hy lar	atte	atte	lagi	agir				£	atio	is "Best in Class"
		α δ Δ	sp	⊳ (do	brat	y di	rap	y sc	sc	vi vi	'n	Ð	Å	#	Facility	Designation	as bench-marked against similar
	1	ner	-ray	X-ra	; cali	x-ra	omo	2-2	(-ra)	X-ra	(-ra)	agir	grap		<u> </u>	Des	capabilities
Beamline Type	Count	Low energy spectros copy	off.	Hard x-ray spectros copy	Optics; calibration; metrology	ard	Macromolecular crystallogra phy	ard	Soft x-ray scattering	Hard x-ray imaging	Soft x-ray imaging	IR imaging	Lithography				worldwide
		7 %	Ø	тs	ŌĒ		25	I	Ø		Ø	뜨		4	NCLC	VIOR	
Hard x-ray diffraction	118			100		100								1	NSLS NSLS		
Hard x-ray spectroscopy Hard x-ray spectroscopy	119			100										1	NSLS		
Hard x-ray spectroscopy Hard x-ray spectroscopy	120			100										1	NSLS		
Optics; calibration; metrology	121			100	100									1	NSLS		
Macromolecular crystallography	122				100		80	20						1	NSLS		
Macromolecular crystallography Macromolecular crystallography	123						100							1	NSLS		
Hard x-ray imaging and soft x-ray spectroscopy and scattering	125		30				100		20	50				1	NSLS		
Hard x-ray diffraction	126					70		30						1	NSLS		
Hard x-ray diffraction and imaging	127					50				50				1	NSLS		
Hard x-ray spectroscopy	128			100										1	NSLS		
Hard x-ray diffraction	129					100								1	NSLS		
Hard x-ray diffraction and scattering	130					50		50						1	NSLS	X16B	
Hard x-ray spectroscopy	131			100										1	NSLS		
Hard x-ray diffraction	132					100								1	NSLS		
Hard x-ray diffraction	133					100								1	NSLS		
Hard x-ray diffraction	134					70		30						1	NSLS		
Hard x-ray spectroscopy	135			100										1	NSLS		_
Hard x-ray spectroscopy	136			80				20						1	NSLS		
Hard x-ray scattering and imaging	137							60		40				1	NSLS		
Hard x-ray scattering, diffraction, and imaging	138					20		40		40				1	NSLS		
Hard x-ray scattering	139					100		100						1	NSLS		
Hard x-ray diffraction	140					100		80						1	NSLS NSLS		
Hard x-ray scattering Hard x-ray scattering	141 142					20		100						1	NSLS		
Hard x-ray scattering	142							100						1	NSLS		
Hard x-ray scattering	143					20		80						1	NSLS		
Hard x-ray scattering Hard x-ray spectroscopy	144			100		20		00						1	NSLS		
Hard x-ray specific copy	145			80		20								1	NSLS		
Hard x-ray spectroscopy and diffraction	147			50		50								1	NSLS		
Optics; calibration; metrology	148				100									1		X24C	
Macromolecular crystallography	149						100							1	NSLS		
Hard x-ray imaging	150									100				1		X26A	
Macromolecular crystallography	151						100							1	NSLS	X26C	
Hard x-ray imaging	152									100				1	NSLS	X27A	
Lithography	153												100	1		X27B	
Hard x-ray scattering	154							100						1		X27C	
Hard x-ray spectroscopy	155			100										1	NSLS	X28C	
Macromolecular crystallography	156						100							1	NSLS	X29	Х

## Beamline Matrix – Stanford Synchrotron Radiation Laboratory (23)

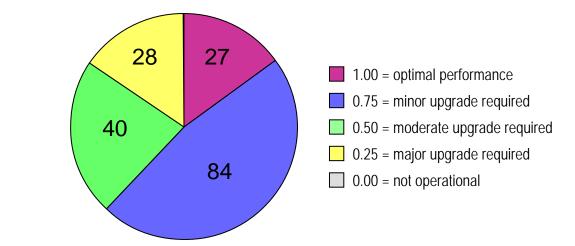
					I	Utiliza	tion N	<i>l</i> atrix	for th	e Fou	r DOE	BES	Light	t Sour	ces		
									NIQUE								
DESCRIPTIONS of 12 TECHNIQUES:		Perc	entage						e on ea <sup>r</sup> each b			The su	um of		_		_
				pe	ercenta	iges eq	uais it	J0 % 10r	eacht	beamin	e.				F	Y 200	4
http://www.sc.doe.gov/bes/synchrotron_techniques/index.htm																	
		S	pectr	oscop	у		Scatt	tering			Imag	ging					
			opy			_		5	_								Ohaali (M) maaaa
			Soft x-ray spectroscop)		2	Hard x-ray diffraction	5	Hard x-ray scattering	scattering	Hard x-ray imaging	ging				-	5	Check (X) means that the beamline
		y py	spec	by .	Optics; calibration; metrology	diffr	Macromolecular crystallography	sca	scat	ima	Soft x-ray imaging	_	>	#	Facility	Designation	is "Best in Class" as bench-marked
		Low energy spectroscopy	ray	Hard x-ray spectroscopy	calib gy	-ray	logn	c-ray	x-ray	(-ray	ray	R imaging	Lithography		Fa	Desi	against similar capabilities
Beamline Type	Count	ectr	oft ×	ardy	otics; etrolo	ard x	acro ystal	ard x	Soft x-	ard	oftx	ime	thog				worldwide
		sp	ŭ	Яg	0 E	Ï	25		ŭ	Ĩ	й	Ĕ	5	- 1	CCDI	1 4	
Hard x-ray scattering Macromolecular crystallography	157 158						100	100						1	SSRL SSRL		
Hard x-ray diffraction	159					100	100							1	SSRL		
Hard x-ray imaging and diffraction	160					40				60				1	SSRL	2-2	
Hard x-ray spectroscopy	161			80	20									1	SSRL		
Lithography	162												100	1	SSRL		
Hard x-ray scattering	163							100						1	SSRL	4-2	
Low energy spectroscopy	164	50	25								25			1	SSRL	5	Х
Hard and soft x-ray spectroscopy and hard x-ray imaging	165		30	40						30				1	SSRL	6-2	
Macromolecular crystallography	166						100							1	SSRL	7-1	
Hard x-ray diffraction	167					100								1	SSRL	7-2	
Hard x-ray spectroscopy	168			100										1	SSRL	7-3	
Low energy spectroscopy and soft x-ray spectroscopy	169	50	50											1	SSRL		
Soft x-ray spectroscopy	170		100											1	SSRL		
Macromolecular crystallography	171						100							1	SSRL		
Macromolecular crystallography	172						100							1	SSRL		X
Hard x-ray spectroscopy	173		100	80						20				1	SSRL		X
Soft x-ray spectroscopy	174		100			10				10				1	SSRL	10-1	_
Hard x-ray diffraction, spectroscopy, scattering, and imaging	175			30		40	100	20		10				1	SSRL	10-2	_
Macromolecular crystallography	176			100			100							1	SSRL	11-1	N N
Hard x-ray spectroscopy	177			100		50	50							1	SSRL SSRL		X
Macromolecular crystallography and hard x-ray diffraction Hard x-ray scattering	178 179					50	50	100						1		11-3 SPPS	X
Hard x-ray scattering	1/9							100						# of	SOILE	SFFS	~
														# of Beamli			
		01	02	03	04	05	06	07	08	09	10	11	12	nes			
		0.00	0.40	5.70	0.20	12.70	11.50	7.00	0.60	4.90	1.00	0.00	0.00	44.00	APS		
Here are some summary statistics for the 179		3.55	5.70	0.25	1.80	3.25	7.70	0.30	0.95	3.50	3.25	1.25	3.50	35.00	ALS		
operating beamlines.		9.80	6.40	11.10	6.00	14.00	9.80	8.80	1.10	4.80	2.00	2.20	1.00	77.00	NSLS		
		1.00	3.05	4.30	0.20	3.30	5.50	3.20	0.00	1.20	0.25	0.00	1.00	23.00	SSRL	1	
			2102		0.20	2.20	2.2.5		0.00		0.20	0.00		20.00			
		14.35	15.55	21.35	8.20	33.25	34.50	19.30	2.65	14.40	6.50	3.45	5.50	179.00	All 4		
		8%	9%	12%	5%	19%	19%	11%	1%	8%	4%	2%	3%	100%			

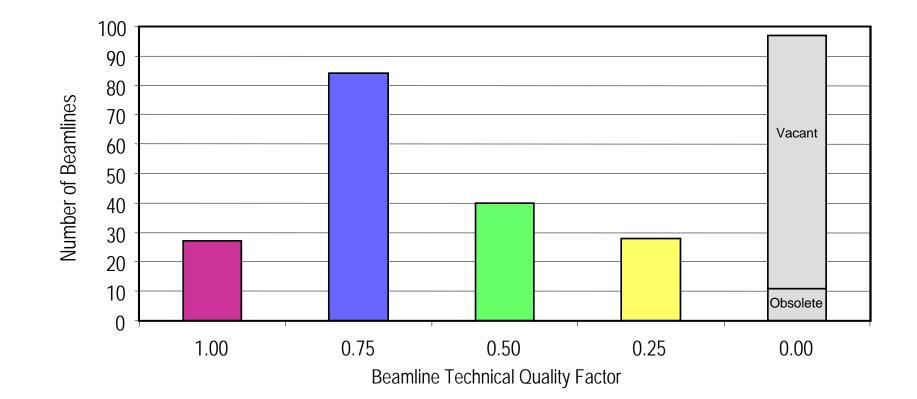
#### Distribution of Beamline Techniques



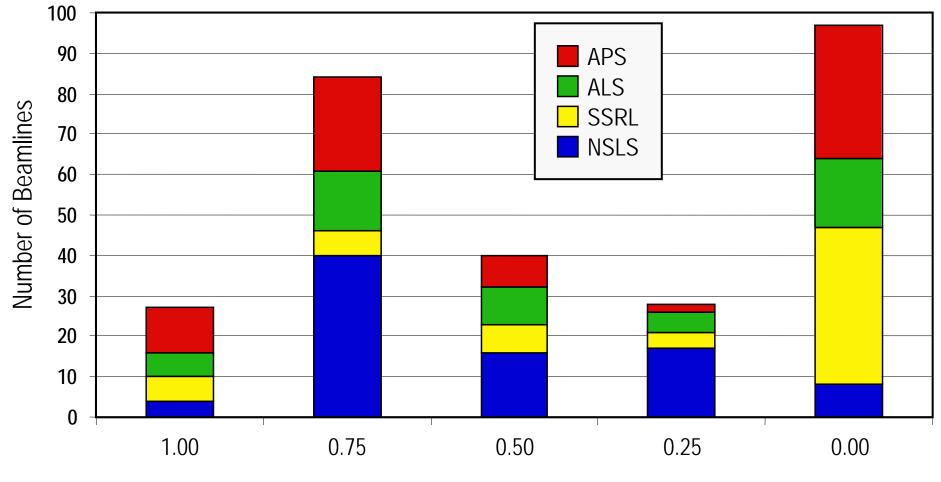
#### **Quality Distribution of 179 Operating Beamlines**

The light sources then rated each beamline according to a quality factor. A "normalization" team consisting of one senior technical staff member from each light source visited the four light sources and spot checked the ratings to ensure uniformity.



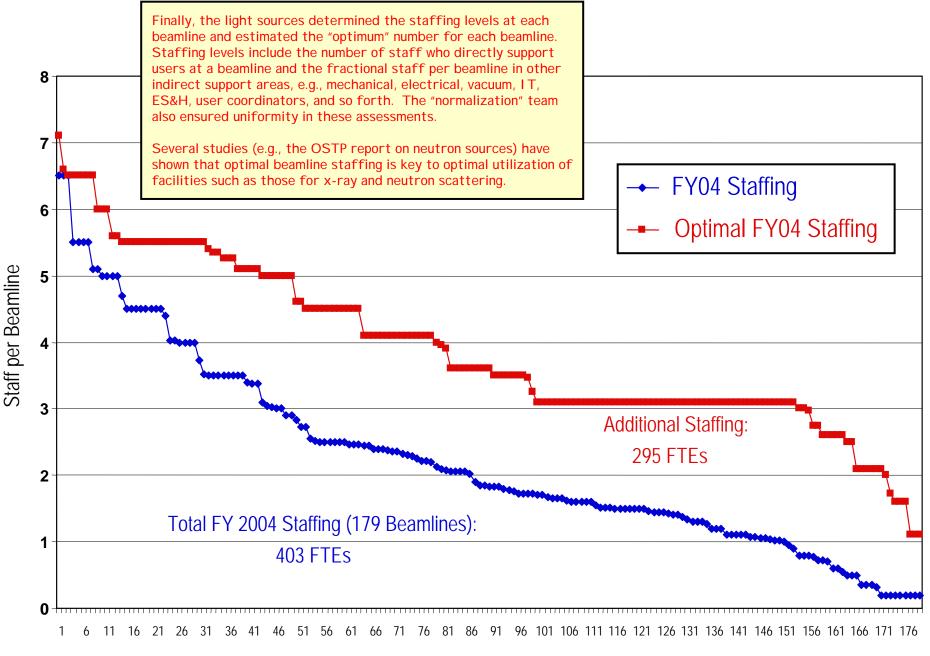


### Beamline Quality Distribution by DOE Light Source Facility

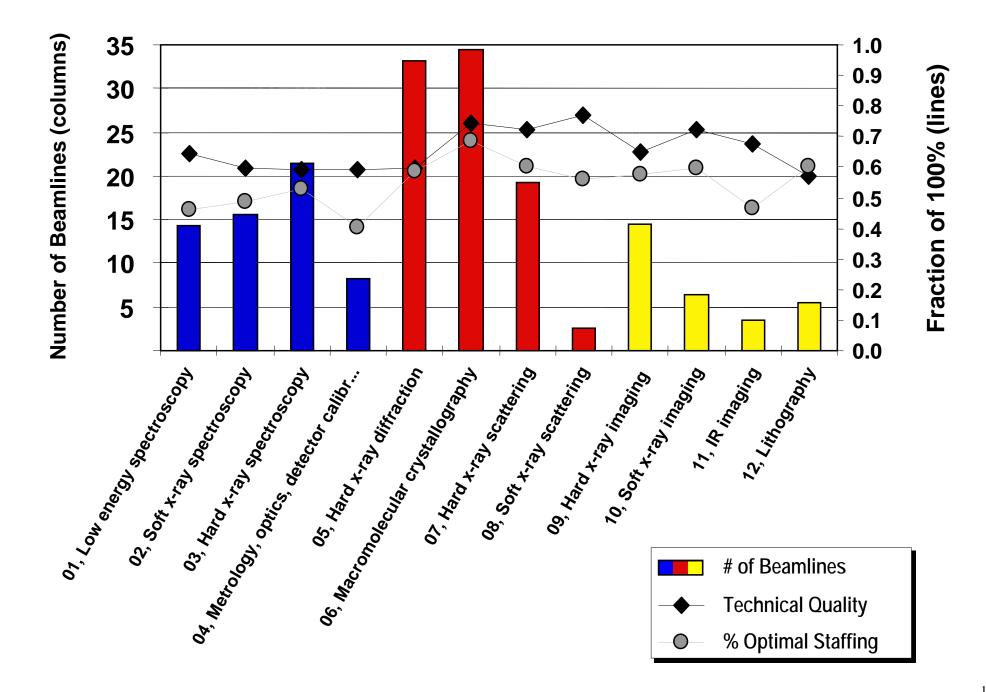


Beamline Technical Quality Factor

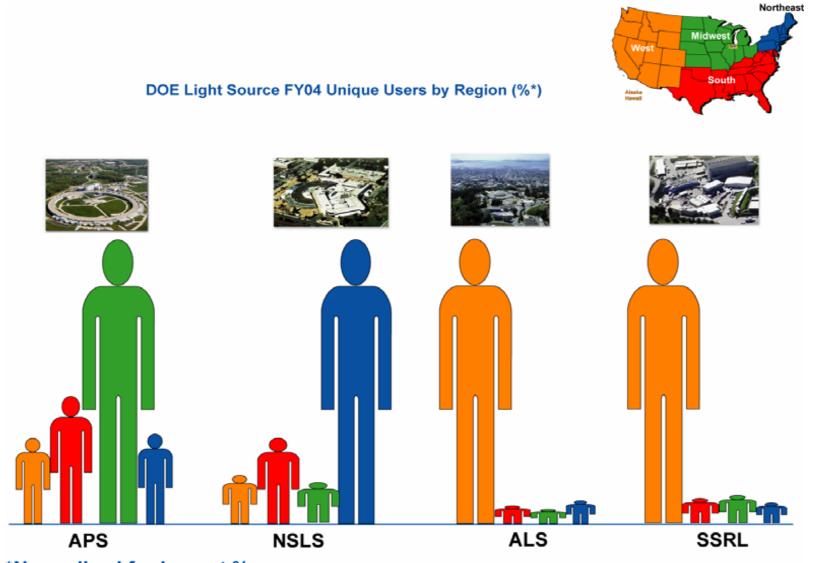
## FY 2004 Beamline Staffing versus Optimal Staffing



#### Beamline Quality Data by Beamline Technique

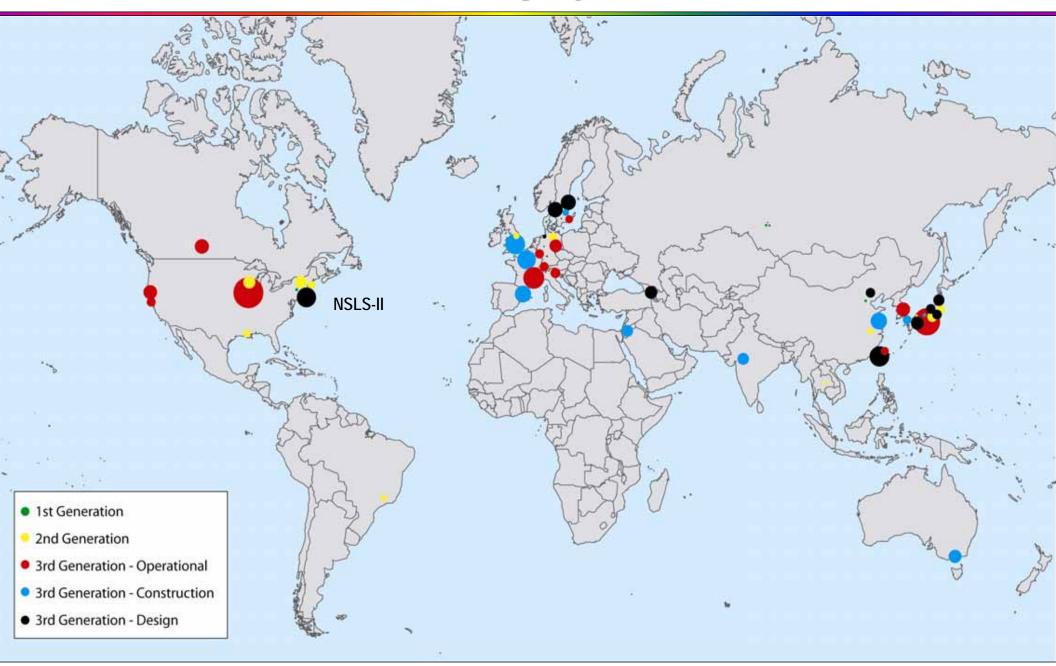


## **User Demographics**



\*Normalized for largest %

#### International Benchmarking: Synchrotrons Worldwide



The dots show all 1st, 2nd, and 3rd generation light sources worldwide that are operational, under construction, and in design. The dot diameter is proportional to the total number of beamlines at each facility. The number of users that a facility can host scales with the number of beamlines. Red, blue, and black dots show 3rd generation machines. The numbers of beamlines for these machines are shown on the next chart.

# Major Light Sources Worldwide

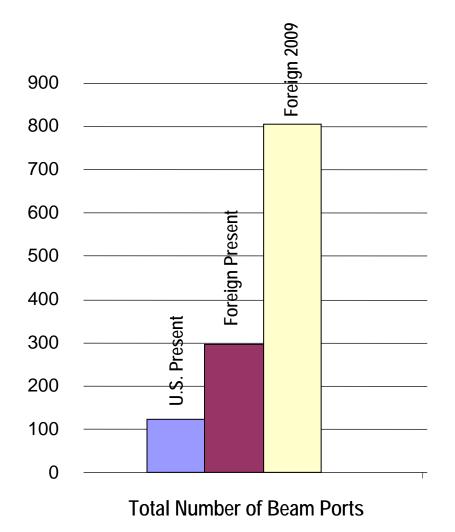
			Gener-		Circum	Current	Horiz Emit	∨ert Emit		Usable Insertion Device	Usable Bending Magnet	Total ID Straights & BM	Bunch Length (ơ <sub>L</sub> )		Top-		Start	Construction Funding
Country	City	Name		E [GeV]	[m]	[ma]	[nm-rad]		Cells	Straights	Ports	Ports	[psec]	Lattice <sup>1</sup>	Off	Status <sup>4</sup>		Commitment
China	Beijing	BSRF	1	2.2	240.4	65	76	7.6	4	3	3	6	83	FODO	N	0	1989	
Denmark	Aarhus	ASTRID	1	0.58	40	250	160	2.2	4	1	4	5	?	DBA	N	0	1990	
Germany	Dortmund	DELTA	1	1.5	115.2	120	16	0.5	16	3	2	5	?	FODO	N	0	1995	N/A
Germany	Bonn	ELSA	1	1.6-3.0	164.4	25-250	760	76	12	0	4	4	?	FODO	Ν	0	1988	N/A
Russia	Novosibirsk	VEPP-4M	1	6	366	100	400	120	4	2	4	6	?	FODO	Ν	0	1998	N/A
Russia	Novosibirsk	VEPP-3	1	2	74	250	270	2.7	2	1	2	3	?	FODO	Ν	0	1973	N/A
Russia	Novisibirsk	VEPP-2M	1	0.7	18	300	460	4.6	3	2	3	5	?	FODO	Ν	0	1972	N/A
Sweden	Lund	MAX-I	1	0.55	90	300	40	1.2	4	1	3	4	80	DBA	Ν	0	1986	
U.S.	lthaca	CHESS	1	5.3	795	190	200	20	?	3	4	7	67	FODO	Ν	0	1980	
Brazil	Campinas	LNLS	2	1.37	93.2	250	100	3	6	4	10	14	?	DBA	Ν	0	1997	N/A
China	Hefei	NSRL	2	0.8	66.1	180	134	4	4	2	12	14	?	TBA	N	0	1991	N/A
England	Warrington	Daresbury SRS	2	2	96	250	150	4.5	8	5	9	14	?	FODO	Ν	0	1981	N/A
Germany	Hamburg	DORIS-III	2	4.5	289	150	432	13	?	10	10	20	?	FODO	Ν	0	1974	N/A
Japan	Tsukuba	PF-AR	2	6.5	377	55	168	1.7	8	4	1	5	29	FODO	Ν	0	1984	
Japan	Okazaki	UVSOR-II	2	0.75	53.2	300	27.4	2.7	8	7	16	23	170	DBA	Ν	0	1983	N/A
Japan	Tsukuba	Photon Factory	2	2.5	187	450	36	0.36	10	6	15	21	33	FODO	Ν	0	1982	N/A
Thailand	Nakhon Ratchasima	NSRC	2	1	81.3	150	226	2.3	4	4	4	8	135	DBA	N	0	2002	N/A
U.S.	Baton Rouge	CAMD	2	1.3	55	200	235	2.4	4	1	16	17	?	DBA	N	0	1992	N/A
U.S.	Madison, WI	ALADDIN-SRC	2	1	88.9	190	108	2.7	4	4	24	28	350	TBA	Ν	0	1985	N/A
U.S.	Upton, NY	NSLS X-ray	2	2.8	170	280	63	0.13	8	7	21	28	145	DBA	Ν	0	1982	N/A
U.S.	Upton, NY	NSLS IR/VUV	2	0.8	51	1000	160	4	4	2	16	18	162	DBA	N	0	1982	N/A
Canada	Saskatoon	CLS	3	2.9	171	200	18	0.36	12	9	24	33	42	DBA	N	0	2004	N/A
France	Grenoble	ESRF	3	6	844	200	3.8	0.023	- 32	27	22	49	20	DBA	N	0	1994	N/A
Germany	Karlsruhe	ANKA	3	2.5	240	110	80	0.24	8	- 5	16	21	?	DBA	N	0	2000	N/A
Germany	Berlin	BESSY-II	3	1.7	240	270	5.2	0.052	16	13	16	29	17	DBA	N	0	1998	N/A
Italy	Trieste	ELETTRA	3	2	260	320	7	0.07	12	11	12	23	18	DBA	N	0	1993	N/A
Japan	Nishi-Harima, Hyogo	SPRING-8	3	8	1436	100	3	0.06	48	38	24	62	15.5	DBA	Ν	0	1997	N/A
Korea	Pohang	PLS	3	2.5	281	180	13	0.13	12	10	22	32	21.2	TBA	Ν	0	1995	N/A
Sweden	Lund	MAX-II	3	1.5	90	250	8.8	0.088	10	8	10	18	20	DBA	Ν	0	1997	
Switzerland	Villigen	SLS	3	2.4	288	400	5	0.05	12	9	12	21	12	TBA	Y	0	2001	N/A
Taiwan	Hsinchu	TLS (NSRRC)	3	1.5	120	200	25	- Î (	6	6	12	18	25	TBA	Ν	0	1993	N/A

# Major Light Sources Worldwide (con't)

Country	City	Name	Gener- ation <sup>3</sup>	E [GeV]	Circum [m]	Current [ma]	Horiz Emit [nm-rad]	∨ert Emit [nm-rad]	Cells	Usable Insertion Device Straights	Usable Bending Magnet Ports	Total ID Straights & BM Ports	Bunch Length (σ <sub>L</sub> ) [psec]	Lattice <sup>1</sup>	Top- Off	Status <sup>4</sup>	Start Ops	Construction Funding Commitment
U.S.	San Francisco, CA	SPEAR3	3	3	240	500	18	0.18	18	14	18	32	19	DBA	Y	0	2004	N/A
U.S.	Chicago	APS	3	- 7	1060	100	3.1	0.031	40	35	35	70	26	DBA	Y	0	1995	N/A
U.S.	San Francisco, CA	ALS	3	1.9	197	400	6.8	0.14	12	9	12	21	40	TBA	Ν	0	1993	N/A
Australia	Melbourne, Victoria	AUST. SYNCH.	3	3	216	200	7	0.07	14	12	18	30	?	DBA	N	С	2007	Yes
China	Shanghai	SSRF	3	3.5	432	300	3	0.03	20	18	20	38	14	DBA	Y	C	2009	Yes
England	Didcot, Oxfordshire	DIAMOND	3	3	561.6	300	2.7	0.027	24	22	24	46	26	DBA	Ν	С	2007	Yes
France	GIF-sur- Y√ETTE CEDEX	SOLEIL	3	2.75	354	500	3.74	0.037	24	21	22	43	13.8	DBA	Y	с	2006	Yes
India	Indore	INDUS-II	3	2.5	173	300	58	5.8	8	5	22	27	?	DBA	N	С	2005	Yes
Japan	Nishi-Harima, Hyogo	NEW SUBARU	3	1.5	119	500	67	6.7	6	4	4	8	26	DBA	Ν	с	2006	Yes
Japan	Tosu, Saga	Saga LS	3	1.4	75.6	300	15	0.15	8	6	14	20	29	DBA	N	С	2005	Yes
Jordan	Allan	SESAME	3	2.5	129	400	26	0.26	8	11	16	27	38	DBA	Ν	С	2009	Yes
Spain	Barcelona	ALBA	3	3	264	400	3.6	0.036	20	18	20	38	?	DBA	Y	D	2010	Yes
Sweden	Lund	MAX-III	3	0.7	36	300	14	1.4	8	7	8	15	75	DBA	N	С	2005	Yes
Armenia	Yerevan	CANDLE	3	3	216	350	8.4	0.084	16	13	16	29	22	DBA	Ν	С	2007	Partial <sup>1</sup>
China	Beijing	BLS	3	2.2	240.4	300	3.3	0.1	8	6	16	22	?	5BA	?	D	?	No
Germany	Hamburg	PETRA-III	3	6	2304	100	1	0.01	9 <sup>2</sup>	9	0	9	40	DBA <sup>2</sup>	Ν	D	2009	Yes <sup>2</sup>
Japan	Sendai	TOHOKU LS	3	1.5	187	300	7.4	0.074	12	10	20	30	14.3	DBA	Ν	D	?	No
	Kashiwa, Chiba	VSX	3	1	249	200	0.75	0.075	4	4	18	22	7.3	Racetrack	Ν	D	?	No
Japan	Okazaki, Aichi	SUPER SOR	3	1.8	280	500	8	0.08	14	12	14	26	13.3	DBA	Y	D	?	No
Japan	Ichihara, Chiba	NANOHANA	3	2	108	300	70	2.1	8	6	16	22	5000	DBA	Ν	D	?	No
Sweden	Lund	MAX-IV-3	3	3	287	500	0.9	0.009	12	11	24	35	?	7BA	Y	D	?	No
Sweden	Lund	MAX-IV-1.5	3	1.5	287	500	0.3	0.003	12	11	24	35	?	7BA	Y	D	?	No
Taiwan	Hsinchu	TLS-II	3	3	240	400	10	0.3	16	14	32	46	?	DBA	?	D	?	No
U.S.	Upton, NY	NSLS-II	3	3	630	500	0.5	0.005	24	21	24	45	12.8	TBA	Y	D	2013	No
1Armenian G	Government funder	d office building a	nd land	, U.S. fun	ded desig	gn; still se	eking full	construct	tion fun	iding comm	nitment. S	ee http://w	ww.cern	courier.com/	main/	article/44	/5/15	

<sup>2</sup>On May 23, 2005, the German Federal Government and the State of Hamburg signed a contrac < the construction of Petra-III. Construction to start in 2007.

### International Benchmarking: 3rd Generation Synchrotrons Worldwide



Considering only beam ports on the 3rd generation sources, this shows that by 2009 the U.S. will be outnumbered by the rest of the world by 7:1 (123 beam ports in the U.S. versus 806 beam ports in the rest of the world).

# Light Sources – Findings and Conclusions from Assessment Study

- I. Light sources have proven to be indispensable for the study of materials structure and function. The number of users has increased by more than a factor of 30 since 1982 and by a factor of 2.5 since 1996, the year of the commissioning of the APS.
- II. The light source accelerator complexes have high availability, dependability, and reliability, delivering more than 95% of scheduled beamtime to the beamports.

#### III. The 2005 study of utilization has shown:

- a. There is unused capacity about 179 beamlines are in service, but another 100 beamlines are not in service.
- b. Beamline instrument technical quality varies considerably, but overall it is below par. Only 15% of in-service beamlines are at optimal quality; 47% need minor upgrades; 22% need moderate upgrade; and 16% need major upgrade.
- c. Beamline staffing is less than 60% of optimal.

#### IV. Additional findings from the BES 2005 peer review of the light sources:

- a. Accelerator staffing is thin at all of the light sources.
- b. Accelerator and beamline components are starting to show the effects of age, even at the newer 3rd generation sources.
- c. Maintenance and improvements (such as top-off mode) are critical to the future success.
- d. Automation employed for macromolecular crystallography beamlines could help overall efficiency in other techniques.
- e. Power cost increases could reduce significantly the number of operating hours at the light sources.

#### V. Additional findings from international benchmarking:

a. Considering only beam ports on the 3rd generation sources, by 2009 the U.S. will be outnumbered by the rest of the world by 7:1.

#### VI. Conclusions:

- a. The U.S. light sources are at a critical point and will fall far below optimum capabilities without increased funding.
- b. Emphasis should be given to upgrading infrastructure and instruments and to providing beamline staff to the world-class facilities.
- c. Investments should be made for minor upgrades such as top-off mode at the world-class facilities.